

8. (Thrice Amended)

C1
A method of manufacturing a thin film negative temperature coefficient thermistor comprising:
selecting a negative temperature coefficient of resistance versus temperature curve;
selecting a mixture of metal film materials to provide the negative temperature coefficient of resistance versus temperature curve while maintaining a desired physical size for the thermistor; and
depositing the mixture of metal film materials on a substrate using a thin film process.

Kindly enter new claims 15 and 16 as follows:

- C2
15. The method of claim 8 wherein the step of depositing is sputter depositing.
16. A method of manufacturing a thin film negative temperature coefficient thermistor, comprising:
selecting a mixture of metal film materials to provide desired negative temperature coefficient of resistance properties while maintaining a standardized physical size and depositing the metal film materials on a substrate using a thin film process.

In the Abstract

Kindly amend the Abstract as follows:

C3
A method for manufacturing a thin film negative temperature coefficient thermistor is disclosed. The method includes selecting a negative temperature coefficient of resistance versus temperature curve, selecting a mixture of metal film materials to provide the negative temperature coefficient of resistance curve while maintaining a desired physical size, and depositing the mixture of metal film materials on a substrate.